

Abstract of the Disclosure

A planet system workpiece support for a vacuum treatment apparatus includes a sun system rotatable in the vacuum treatment apparatus about a sun system axle to be coupled to a drive. At least one planet system is rotatable on planet axle and is supported on the sun system. The planet system has a driving coupling for driving the planet system and the support has at least one moon system supported on the planet system and rotatable about a moon axle with a driving connection to the sun system. At least one workpiece is received on the moon system and the driving connection is established, at least during operation, uninterruptedly between sun system and moon system.